

## IWLPC Sessions at a Glance

<b>Tuesday, October 24, 2017</b>			
7:00am	<b>Registration Opens</b>		
	<b>Session 1</b> WLP - 8:00am-10:00am (Oak) <b>WLP Materials</b>	<b>Session 2</b> 3D - 8:00am-10:00am (Pine) <b>Heterogeneous Integration Enablement</b>	<b>Session 3</b> Advanced Manufacturing & Test - 8:00am-10:00am (Cedar) <b>Test</b>
8:00am	Low Temperature Curable PI/PBO for Wafer-Level Packaging <i>Daisaku Matsukawa, Ph.D., Hitachi Chemical DuPont MicroSystems, Ltd.</i>	Connectivity Management of Vertically Integrated Multi-Substrate Heterogeneous Packages <i>Keith Felton, Mentor Graphics and Magesh Govindarajan, Qualcomm Technologies</i>	Have you Designed for Manufacturing Test? <i>Gerard John, Amkor Technology</i>
8:30am	Enabling Fan-Out Wafer-Level Package (FOWLP) Through Innovative Lithography and Electrodeposition Technology <i>Bryan Buckalew, Lam Research</i>	Underfill Dispensing for Chip-On-Wafer <i>Akira Morita, Nordson Asymtek</i>	Contactor Materials & Impacts on Tip Wear & Life for WLCSP Testing <i>Jiachun(Frank) Zhou, Smiths Interconnect</i>
9:00am	Hitoshi Onozeki, <i>Hitachi Chemical Co., Ltd.</i>	Application of IR Inspection to TCB and Die Placement Processes <i>Justin Brubaker, Kulicke &amp; Soffa Industries</i>	Hybrid Copper Dielectric Direct Bonding of 200 mm CMOS Wafers with Five Metal Levels: Morphologic, Electrical and Reliability Characterization <i>Celso Cavaco, Ph.D., imec</i>
9:30am	Novel Low-temperature Curable Positive-Tone Photosensitive Dielectric Materials with High Elongation for Panel Level Package <i>Hitoshi Araki, Ph.D., Toray Industries, Inc.</i>	Comparison of Different Communication Interfaces between Chips Assembled onto Silicon Interposer <i>Andy Heinig, Fraunhofer IIS/EAS</i>	WLCSP Test Strategy <i>Michael Frazier, Xcerra Corporation</i>
10:00am	<b>Networking Break &amp; Interactive Presentations (10:00am-1:00pm)</b> <b>Exhibit Hall</b>  Presenters: Interconnect Reuse Resolution and Verification with Bum Compensation for HDAP Designs <i>Zain Ali, Mentor Graphics</i>  Application of Picosecond Ultrasonics for Advanced Packaging Process Monitoring and Control <i>Priya Mukundhan, Rudolph Technologies</i>  3D Wafer Level Compression Molding Technology Development For CMOS Image Sensor <i>Tony Curtis, FCI- Huatian Technologies</i>		
10:45am	<b>Welcome Comments</b> Oak Ballroom (2nd Floor) Curtis Zwenger, Amkor Technology IWLPC General Chair		
11:00am	<b>KEYNOTE ADDRESS: The next step in Moore's law: Getting Rid of the Package and Replacing the Printed Circuit Board</b> (Oak Ballroom) <i>Subramanian Iyer, Ph.D.</i> Distinguished Chancellor's Professor, University of California, Los Angeles Chair: Curtis Zwenger, Amkor Technology		
11:45am	<b>Lunch Break</b>		
	<b>Session 4</b> WLP - 1:00pm-3:00pm (Oak) <b>WLP Processes</b>	<b>Session 5</b> 3D - 1:00pm-3:00pm (Pine) <b>Novel Materials/Innovative Equipment</b>	<b>Session 6</b> Advanced Manufacturing & Test - 1:00pm-3:00pm (Cedar) <b>Productivity 1</b>
1:00pm	The Dual Layer Bonding Platform as a Technical Enabler for Wafer-Level Packaging Applications <i>Xiao Liu, Ph.D., Brewer Science Inc.</i>	Photo-Sensitive Insulation Film for Encapsulation and Embedding <i>Kiichi Fukuhara, Ph.D., Hitachi Chemical Co., Ltd.</i>	Rc Management for Next Generation PVD UBM/RDL Metallization Schemes <i>Nick Knight, SPTS Technologies Ltd.</i>
1:30pm	Critical Process Parameters for DPSS Laser Debonding <i>Thomas Uhrmann, EV Group</i>	The Benefits of Source Die Input Flexibility in a TCB Process <i>Tom Strothmann, Kulicke &amp; Soffa Industries</i>	Die-Level Traceability Using Adaptive Patterning <i>Craig Bishop, Deca Technologies</i>
2:00pm	Direct Write Lithography Approach for Wafer-Level Package <i>Hiroshi Matsui, SCREEN Semiconductor Solutions</i>	TMV Solutions Without Wet Chemistry <i>Catherine Shearer, Ormet Circuits, Inc.</i>	Temporary Bonding for High Temperature Processing of Willow Thin Glass <i>Robert Bellman, Ph.D., Corning, Inc.</i>
2:30pm	Electrical and Reliability of Ultra-fine Line Multi-Redistribution Layers Enabled by an Innovative Excimer Laser Dual Damascene Process for Wafer-Level Packaging <i>Habib Hichri, Ph.D., SUSS MicroTec Photonic Systems Inc.</i>	Flip-Chip Bonder Dedicated to Direct Bonding for Production Environment <i>Pascal Metzger, SET</i>	Transfer of Wafer-Level Packaging to Panel Format <i>Christian Onde, Ph.D., Atotech Deutschland GmbH</i>
3:00pm	<b>Networking Break</b> Exhibit Hall		
3:30pm	<b>Panel Discussion: Scaling Up Panel Level Processing: Challenges and Opportunities</b> Oak Ballroom (2nd Floor) Moderators: <i>Jan Vardaman, TechSearch International, Inc. and Ira Feldman, Feldman Engineering Corp.</i>		
4:15pm - 5:30pm	<b>Networking Reception</b>		

Wednesday, October 25, 2017			
7:30am	Registration Opens		
8:30am	<b>KEYNOTE ADDRESS: Samsung's FOPLP: Beyond Moore</b> (Oak Ballroom) <i>Richard (Kwang Wook) Bae</i> <i>Vice President, Corporate Strategy &amp; Planning, Samsung Electro-Mechanics</i> Chair: Chris Scanlan, Deca Technologies		
9:15am	Networking Break Exhibit Hall		
	<b>Session 7</b> WLP -9:45am-11:45am (Oak) <b>Design and Process Technologies</b>	<b>Session 8</b> 3D - 9:45am-11:45am (Pine) <b>Processing Technologies, Challenges and Schemes</b>	<b>Session 9</b> Advanced Manufacturing & Test- 9:45am-11:45am (Cedar) <b>Productivity 2</b>
9:45am	New CAD Tools Feature for Virtual Prototyping <i>Tom Whipple, ZUKEN Inc.</i>	Fan Out eWLB Technology as an Advanced System-in-Package Solution <i>Jacinta Aman Lim, STATS ChipPAC</i>	Wafer Thinning In-Line Inspection Process Control Solution for High Volume Manufacturing <i>Cleonisse Serreccchia, UnitySC</i>
10:15am	Performance of Wafer-Level Interconnects in Metal-Embedded Chip Assembly (MECA) Technology <i>Florian Herrault, Ph.D., HRL Laboratories</i>	Integration of a Chemically-Amplified Photoresist and an Advanced Packaging Stepper for Advanced Packaging Technologies <i>Jack Mach, Rudolph Technologies</i>	Fine Pitch Cu Pillar Assembly Challenges for Advanced Flip Chip Package <i>Nokibul Islam, Ph.D., STATS ChipPAC</i>
10:45am	New Method for Embedding Power Semiconductors for Next Generation Electro-Mobility Requirements <i>Cassandra Melvin, Atotech Deutschland GmbH</i>	Development of Hybrid Bond Interconnect Technology for Die- to-Wafer and Die-to-Die Applications <i>Gullian Gao, Ph.D., Xperi</i>	Process and Productivity Results from a Carrier-Based Linear Transport PVD System for RDL Seed Layer Deposition in Fan-Out Packaging Applications <i>Paul Werbaneth, Intevac, Inc.</i>
11:15am	Fine Pitch Plating Resist for High Density FO-WLP <i>Kenji Okamoto, JSR Corporation</i>	Dual side Chip Cooling Realized by Microfluidic Interposer Processing on 300mm Wafer Diameter <i>Wolfram Steller, Ph.D. Fraunhofer IZM ASSID</i>	Fast Automated Wafer-Level Test Scheme for In-Line Quick Functional Reliability <i>Krishna Mohan Chavali, GLOBALFOUNDRIES Inc.</i>
11:45am	Lunch Break		
1:00pm	<b>KEYNOTE ADDRESS: Innovative Packaging Technologies Usher in a New Era for Integration Solutions</b> Oak Ballroom <i>Han Byung Joon, Ph.D.</i> <i>Chief Executive Officer, STATS ChipPAC</i> Chair: Chris Scanlan, Deca Technologies		
1:45pm	Networking Break		
	<b>Session 10</b> WLP - 2:15pm-4:15pm (Oak) <b>Fan-Out WLP</b>	<b>Session 11</b> 3D - 2:15pm-4:15pm (Pine) <b>Smart System Integration and Applications</b>	<b>Session 12</b> Advanced Manufacturing & Test - 2:15pm-4:15pm (Cedar) <b>Inspection and Metrology</b>
2:15pm	Fan- Out WLP Technology as Sensor Packaging Solution <i>Lewis (In-Soo) Kang, nepes Corporation</i>	Technology Trends for Sensors using WLP and 3D TSV Integration <i>Romain Fraux, Systems Plus Consulting</i>	Advanced Packaging Inspection Solutions for FOPLP Processing <i>Benjamin Meihack, P.E., Rudolph Technologies</i>
2:45pm	Fan-Out Package Technology Based SiP for Advanced RF and High Performance Applications <i>Gaurav Sharma, GLOBALFOUNDRIES US Inc.</i>	Micro Thin-film Li-ion Battery Stacking Technology by Backside Via Last TSV for IoT Devices <i>Takahide Murayama, ULVAC, Inc.</i>	Optical Inspection Solutions for Fan Out Wafer and Panel-Level Packaging Modules <i>Shye Shapira, Ph.D., Camtek</i>
3:15pm	Challenges of Ball-Attach Process Using Flux for Fan Out Wafer/Panel Level Packaging <i>Yan Liu, Ph.D., Indium Corporation</i>	3D Integration for Mobile Security – A Secure Smart Card Application <i>René Puschmann, Fraunhofer IZM ASSID</i>	TBA
3:45pm	Fan Out Wafer and Panel Level Technology for Advanced LED Packaging <i>Tanja Braun, Ph.D. Fraunhofer IZM</i>	Package Assembly Design Kits - The Technology Bridge between Chip Design and Wafer-Level Manufacturing and Assembly <i>Jonathan Micksch, Amkor Technology</i>	Inspection Challenges in Fan Out Level Packaging <i>Woo Young Han, Rudolph Technologies</i>
4:15pm	Conference Ends		

Thursday, October 26, 2017			
7:30am Registration Opens			
Workshop#	Instructor	Time/Room	Topic
WS1	John Lau, Ph.D., ASM Pacific Technology	8:30am-12:00pm   San Carlos	Fan-Out Wafer-Level Packaging and 3D Packaging
WS2	John Hunt, ASE (US) Inc.	8:30am-12:00pm   San Martin	Fan Out Packaging - Technology Overview and Evolution
WS3	Fernando Roa, Ph.D., Amkor Technology	1:30pm-5:00pm   San Carlos	Package on Package Design, Process and Quality
WS4	Rao Tummala, Ph.D., Georgia Institute of Technology	1:30pm-5:00pm   San Martin	Future of Packaging: Embedded and Non-Embedded Format